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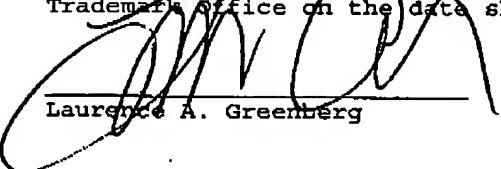
Attorney's Docket No. MUH - 12818

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CERTIFICATION OF MAILING OR TRANSMISSION

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Laurence A. Greenberg

May 15, 2006
Date

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/675,049 Confirmation No.: 5871
Applicant : Ioannis Dotsikas
Filed : September 30, 2003
Title : Method and Furnace for the Vapor Phase Deposition of Components onto Semiconductor Substrates with a Variable Main Flow Direction of the Process Gas
Art Unit : 2818
Examiner : Dung Anh Le
Customer No. : 24131

A M E N D M E N T

Mail Stop Fee Amendment
Hon. Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

S i r :

Responsive to the Office action dated February 16, 2006,
kindly amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 9 of this paper.

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